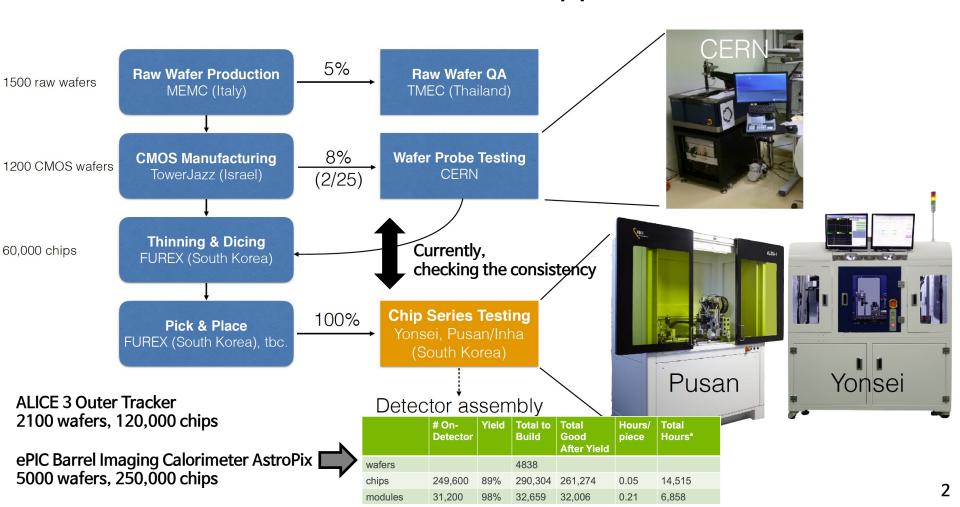
# Wafer QC probing overview

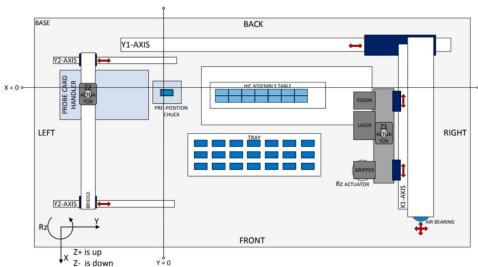
Sanghoon Lim
Pusan National University

# Overview of chip production and test for ALICE ITS2



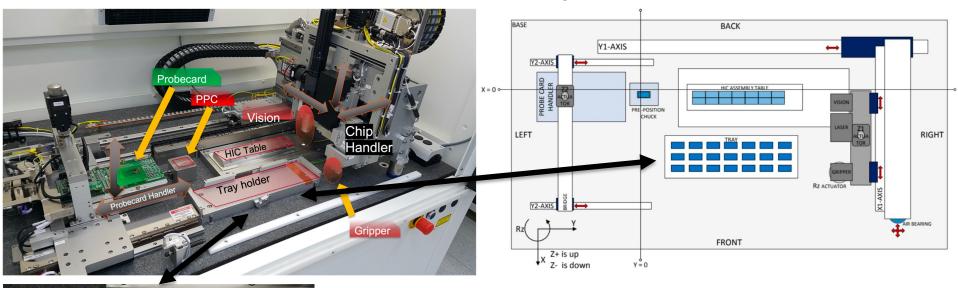
# Chip Handler

# Chip test machine (ALICE ITS2, ALICIA)

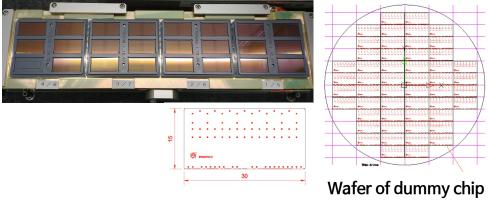


- Two PCs control the chip test system
- One (right) PC to control the chip handler
- Another (left) PC to control the probe card
- Two PCs are communicating to check the status and transfer test results

# Chip test machine (ALICE ITS2, ALICIA)



- Dummy AstroPix chips with bonding pads
- With a new tray, the operation of the chip handler can be customized for AstroPix
- Wafer-level chips can be also used for the wafer probe later



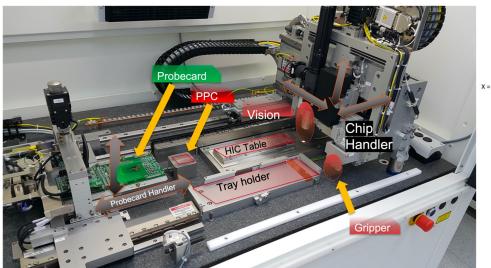
# Preparation for development of chip test procedure

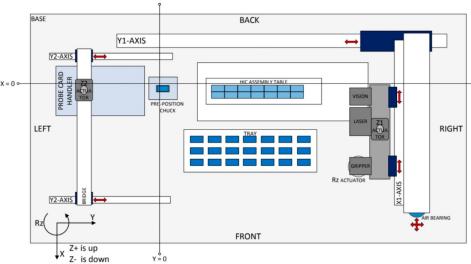
- Preparation for a setup to develop the chip test procedure
  - Tune up an automatic chip handler machine for various chip design
  - Plan to verify the performance by comparing it with the reference results (ALPIDE chip tested by ALICIA)
  - Plan to contact the ALICIA manufacturer for customizing
- Search for a local company working on wafer probing
  - Will have an initial discussion based on the mass chip test of ALPIDE (ALICE ITS2)



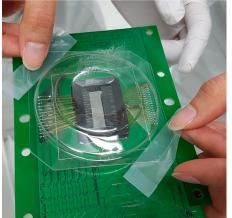


# Chip test machine (ALICE ITS2, ALICIA)





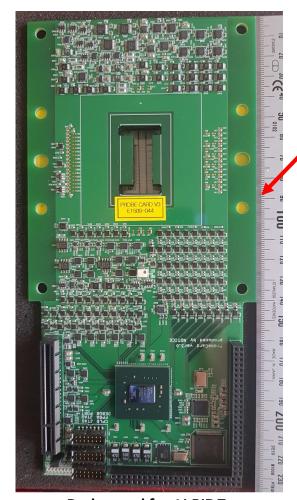


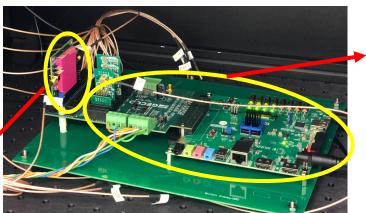


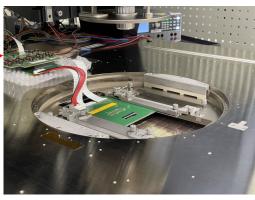
#### ALPIDE single-chip test bench



#### Probe card for AstroPix v3

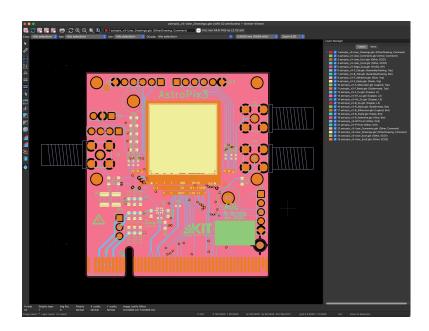


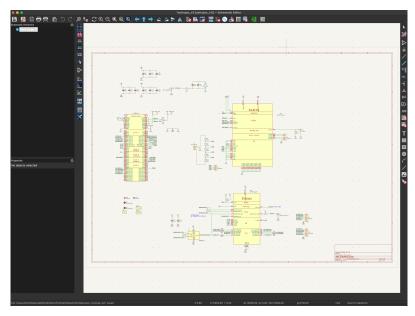




- Initial version for AstroPix v3:
   a simple version for the carrier card only
- Considering the same dimension as the ITS2 probe card to utilize the ALICIA machine for the initial test
- GRECO and FPGA development boards can be connected with flexible cables

#### Probe card for AstroPix v3



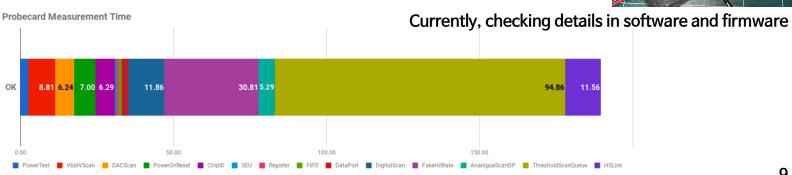




- Received design files for AstroPix v3 single chip carrier board and bonding pads
- Working with a local company (NOTICE) to design a probe card
   Received initial feedback today and will keep communicating with NOTICE
- Firmware and software of AstroPix v3

### Chip test procedure (ALPIDE)

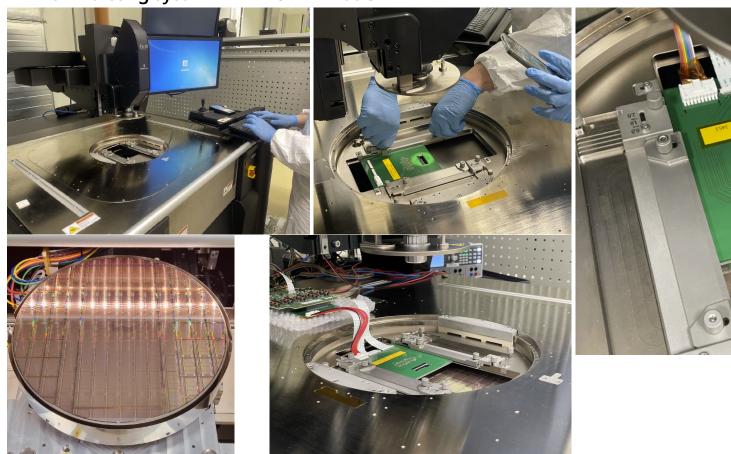
- **Powering test:** just power on/off
- $V_{bb}$  I-V test: apply the reverse substrate bias from 0 V down to -6 V
- DAC scan: verify that each DAC is working by scanning through all its code words
- **Power on reset test:** check the functionality of power on reset
- **SEU check:** monitor the SEU counter and the flag bits on idle operation
- Register test: check all registers by writing and reading back to find stuck bit
- FIFO test: check all the generated memory blocks
- Data port test: verify its functionality to send quasi-static patterns in case of the readout test failure
- Digital scan: inject single hits directly into the in-pixel memories and read back
- Fake hit rate: measures the number of noisy pixels and faulty front-ends
- Analog scan DP: exercise the analog front-end and the full readout chain of ALPIDE
- Threshold scan: test all analog front-ends/pixels by using analog pulse injection
- **High speed link check:** check its functionality





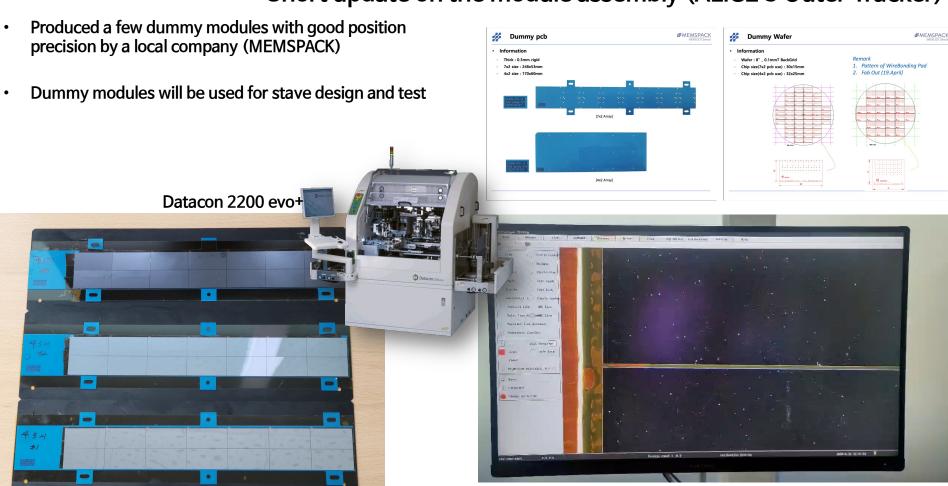
# Preparation for development of chip test procedure

Wafer testing system for ALICE ITS3 at CERN





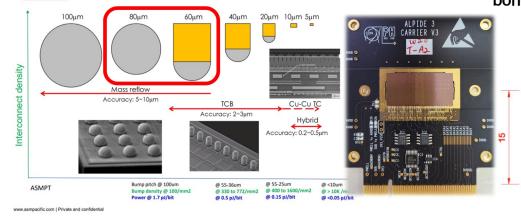
# Short update on the module assembly (ALICE 3 Outer Tracker)

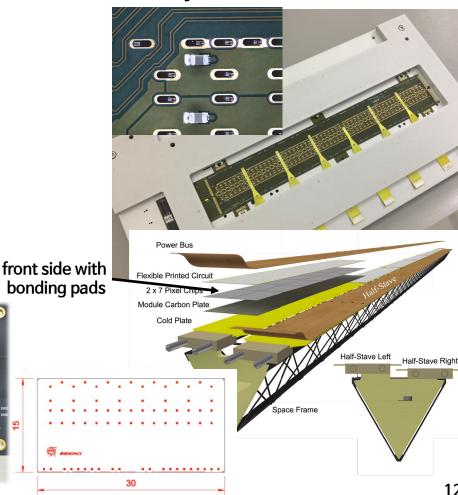


# Short update on the module assembly (ALICE 3 Outer Tracker)

- Recently have an initial discussion about bonding
- ITS2 OB used wire bonding to connect FPCB and bonding pads spread through the entire surface area
  - Experienced some failures of wire bonding due to epoxy covering the bonding pads
- Plan to test different types of bonding with dummy chips: wire bonding with pad at the single edge bump bonding with and without epoxy

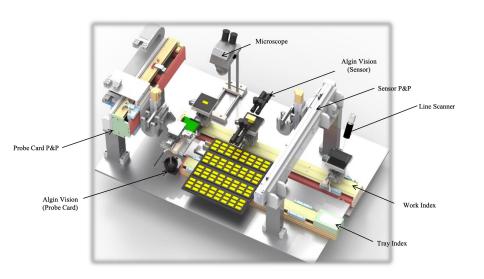


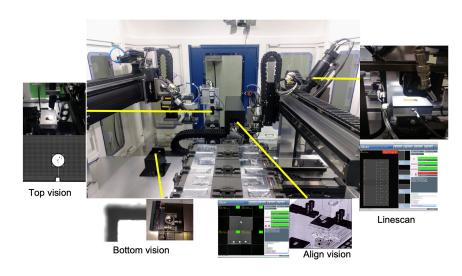




# **BACKUP**

# Chip test machine (ALICE ITS2, COREA-YS-01)



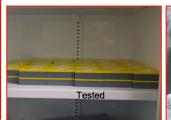


#### A simpler version of the machine dedicated to chip test













Arrival scan

Sensor preparation

Fully automated test and remote control

Storage inside cabinet

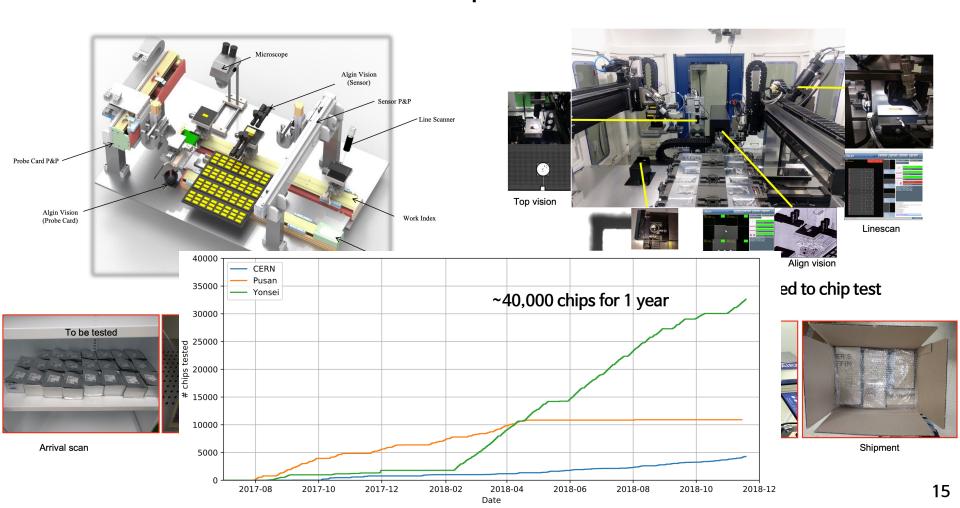
Packaging for shipment

Shipment

Class 100, ~10 min.

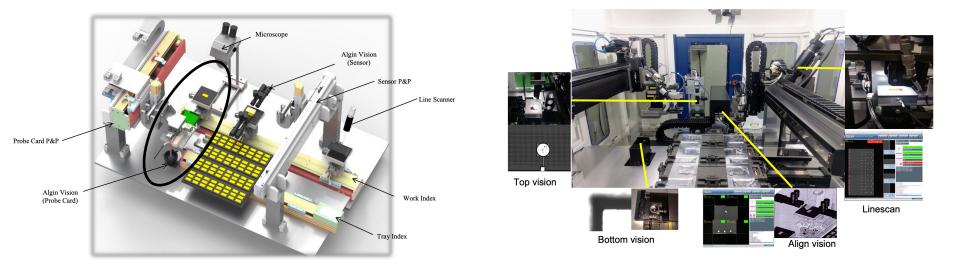
Class 10, ~10 hours

# Chip test machine (ALICE ITS2, COREA-YS-01)

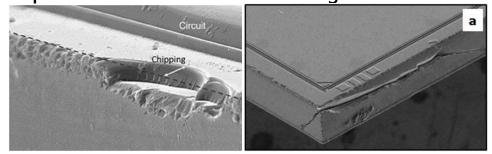


# Preparation for development of chip test procedure

One possible option: chip-level tests with multiple probe cards doing tests in parallel



It depends on the failure rate from dicing



Chip test machine (ALICE ITS2, ALICIA)

